# III-V MBE System Model 35-3

# Engines for Thin Film Innovation



# SVT Associates' Model 35-3

- SVT Associates' Model MBE 35-3 is a research MBE System for growth of thin films on 3" (4" capable) substrates. It includes vacuum chambers, pumps, gauges, effusion cell sources, control electronics and power supplies, computer system and software.
- The load-lock introduction Chamber allows for rapid sample loading while maintaining the high purity environment.
- The UHV Growth Chamber includes a series of source ports to accommodate a wide selection of deposition sources and process monitoring tools.
- The substrate growth manipulator provides temperatures up to 1000 C and continuous rotation during MBE growth.
- The RoboMBE automation software/system provides for recipe control of the MBE process.
- Demo and deposition services available.

## SVT Associates, Inc.

- Leading manufacturer of thin film deposition equipment since 1993.
- In-house laboratory for materials research and process development.
- Established a diverse range of deposition components, systems, integrated sensors, and process control.
- Developed strong combination of equipment manufacturing and process know-how.
- Seven Applications Laboratory deposition systems producing world class materials.
- Diverse system product line spanning the thin film deposition market.
- Leading supplier with over 190 systems in the field.

# **Applications**

- GaAs
- GaSb
- AlGaAs
- AlGaSb
- AlAs
- AISb
- InAlAs
- InAlSb



# Specifications Model 35-3

#### **BASE SYSTEM**

#### Chamber and Vacuum Pumps

12" Access Flange

1,500 l/s Cryo Pump

(300 l/s Turbo Pump Available)

200 l/s Ion Pump

Integrated Cryo-Shroud

Base Pressure: 8x10<sup>-11</sup> torr

## **Deposition Sources**

Up to Ten Effusion Cells with

Pneumatic Shutters

#### Valve Cracking Sources for As/Sb

Two temperature zones

Power Supplies and Controllers for Valved Cracker - As/Sb

Model VC-MRS: Servo Motor Package for Valved Cracker

### Deposition Stage

3" (4" Capable) Sample Size

Heating to 1,000 C

Continuous Rotation

z-Axis Translation

Master Shutter

## In-Situ Process Monitoring Tools Available

RHEED, 10 - 15 keV Electron Source

RHEED, Screen, Viewport, and Shutter, Pb glass

Quartz Crystal Deposition Rate Monitor

Linear Flux Monitor

AccuFlux Process Monitor

AccuTemp Process Monitor

#### Gauges

Full Range Microlon Gauges

**UHV** Ion Gauges

## Automation Package:

Pressure Readout

Auto Pump Down and Venting

Stage Heating and Rotation

**Growth Recipe Control** 

Safety Interlocks

#### Load Lock

Quick Access Door

80l/s Turbo Pump

Six Position Sample Cassettes

Magnetically Coupled Transfer Arm

#### Additional Features

Integrated Bakeout



